



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/212,726
Filing Date December 15, 1998
Inventor Klaus Florian Schuegraf
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner Erik J. Kielin
Attorney's Docket No. MI22-1098
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO₂ on
a Substrate

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References –See Attached Form PTO-1449

The Examiner's attention is directed to the reference which is listed on the attached Form PTO-1449, a copy of the abstract of which is attached. No admission is made regarding whether the submitted reference is prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

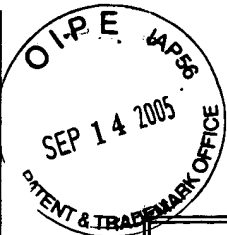
Dated: September 14, 2005

By: Jennifer J. Taylor
Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

09/20/2005 EAYALEW1 00000015 09212726

01 FC:1806

180.00 OP



Sheet 1 of 1

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1098		SERIAL NO. 09/212,726		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Klauf Florian Schuegraf				
				FILING DATE December 15, 1998		GROUP 2813		
U.S. PATENT DOCUMENTS								
*Examine r Initial		Document Number	Date	Name	Class	Sub- class	Filing Date If Appropriate	
	AA	4,767,429	08-1988	Fleming et al.				
	AB	5,593,741	01-1997	Ikeda				
	AC							
	AD							
	AE							
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Sub- class	Translation	
							Yes	No
	AL	JP03125930	04-1992	Japan				
	AM	JP08130245	05-1996	Japan				
	AN							
	AO							
	AP							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AQ							
	AR							
	AS							
EXAMINER				DATE CONSIDERED				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								